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Attorney Docket No.: MTI-31470

HE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Zheng, Lingyi A.

Serial No.

09/912,041

Confirmation No.

4539

Filing Date

July 24, 2001

For:

Improved Cell Nitride Nucleation on Insulative Layers and

Reduced Corner Leakage of Container Capacitors

CERTIFICATION UNDER 37 CFR 1.8(a) and 1.10

I hereby certify that, on the date shown below, this correspondence is being:

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INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. §1.97/98

In compliance with Applicant's duty of disclosure as set forth in 37 C.F.R. §1.56, listed on the attached equivalent to Form PTO-1449 are those patents and other publications known to the Applicant which may be considered material to the patentability of the claims of the above-captioned application.

The Applicant respectfully requests that the documents listed on the attached equivalent to Form PTO-1449 be considered by the Examiner, that these references be made of record in the present applicant, and that an initialed copy of the attached equivalent to Form PTO-1449 be returned to the undersigned in accordance with MPEP 609.

Respectfully submitted,

Dated:

Une 15

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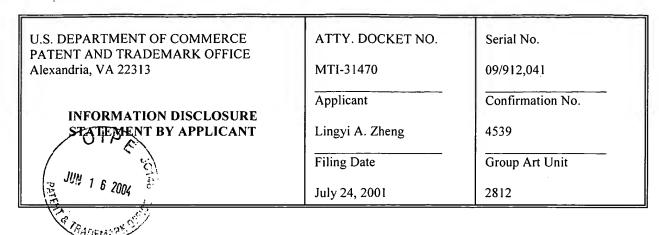
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MKE/947248.1

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OTHER DOCUMENTS (Including Author, Title, Date, Relevant Pages, Place of Publication)

Examiner Initial		Non-Patent Document
	A1	Van Zant, Peter, Microchip Fabrication, A Practical Guide to Semiconductor Processing, 4 th ed., McGraw-Hill, New York, pp. 337-357 and 363-366 (2000)
	A2	Wolf and Tauber, Silicon Processing for the VLSI Era, Vol. 1: Process Technology, 2 nd ed., Lattice Press, Sunset Beach, Cal., pp. 202-206 and 371-433 (2000)

Examiner Initials Date Considered

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.